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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/082,769	02/25/2002	George G. Barclay	51065	4396
7590 09/04/2008 ROHM AND HAAS ELECTRONIC MATERIALS LLC 455 FOREST STREET MARI POROLICH MA 01752			EXAMINER	
			WALKE, AMANDA C	
MARLBOROUGH, MA 01752			ART UNIT	PAPER NUMBER
			1795	
			MAIL DATE	DELIVERY MODE
			09/04/2008	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

	Application No.	Applicant(s)			
	10/082,769	BARCLAY ET AL.			
Office Action Summary	Examiner	Art Unit			
	Amanda C. Walke	1795			
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the c	orrespondence address			
A SHORTENED STATUTORY PERIOD FOR REPL' WHICHEVER IS LONGER, FROM THE MAILING D.  - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tin will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	N. nely filed the mailing date of this communication. D (35 U.S.C. § 133).			
Status					
1) ☐ Responsive to communication(s) filed on <u>05 N</u> 2a) ☐ This action is <b>FINAL</b> . 2b) ☐ This      3) ☐ Since this application is in condition for alloware closed in accordance with the practice under Expression in the practice of the practice.	action is non-final. nce except for formal matters, pro	secution as to the merits is			
Disposition of Claims					
4) ☐ Claim(s) 37-40,45-47 and 49-57 is/are pending 4a) Of the above claim(s) is/are withdray 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 37-40, 45-47, and 49-57 is/are rejected to. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	wn from consideration.				
Application Papers					
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) acc Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Example 11.	epted or b) objected to by the I drawing(s) be held in abeyance. See tion is required if the drawing(s) is ob	e 37 CFR 1.85(a). lected to. See 37 CFR 1.121(d).			
Priority under 35 U.S.C. § 119					
<ul> <li>12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).</li> <li>a) All b) Some * c) None of:</li> <li>1. Certified copies of the priority documents have been received.</li> <li>2. Certified copies of the priority documents have been received in Application No.</li> <li>3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* See the attached detailed Office action for a list of the certified copies not received.</li> </ul>					
Attachment(s)  1) Notice of References Cited (PTO-892)  2) Notice of Draftsperson's Patent Drawing Review (PTO-948)  3) Information Disclosure Statement(s) (PTO/SB/08)  Paper No(s)/Mail Date	4)  Interview Summary Paper No(s)/Mail Da 5)  Notice of Informal P 6)  Other:	ate			

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## **DETAILED ACTION**

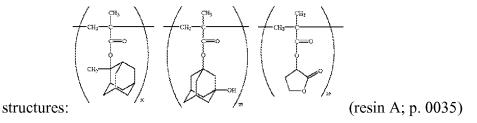
## Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 6/23/2008 and 11/5/2007 have been entered.

## Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 37-40, 45-47, and 49-57 are rejected under 35 U.S.C. 103(a) as being unpatentable over Fujishima et al. (EP 982628 A2) with Rahman (US 6610465 B2) cited to show inherent in view of Willson et al. (US 6103445 A).

Fujishima exemplifies the synthesis of resin A and resin H that have the following



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$$\begin{array}{c|c} CH_3 & CH_3 \\ CH_2 \cdot C & CH_2 \cdot C \\ C=O & CEN \\ C_2H_3 & CH_2 \cdot C \\ C_2H_3 &$$

(resin H; p. 0043). See also resins C, D, I and J. Example 7

forms a photoresist composition comprising resin H; p-tolyldiphenylsulfonium trifluoromethanesulfonate as an acid generator; 2,6-diisopropylaniline as a quencher; and 2-heptanone as the solvent. The said composition was applied to a silicon wafer; exposed using a KrF excimer stepper; and developed to form a pattern (p. 0047-0049). Example 11 forms a photoresist composition comprising resin A; p-tolyldiphenylsulfonium perfluorooctane sulfonate as an acid generator; 2,6-diisopropylaniline as a quencher; and propylene glycol monomethyl ether acetate and  $\gamma$ -butyrolactone as the solvent mixture. The said composition was applied to a silicon wafer; exposed using an ArF excimer stepper; and developed to form a pattern (p. 0052-0054). See also example 3.

It is the examiner's position that the second monomer in each of resins A and H meets the limitation of a hydroxyadamantyl moiety. The third monomer of resin A meets the limitations of a lactone which is readily acid labile. The hydroxyadamantyl methacrylate is also readily acid labile. This position is supported by the teachings of Rahman which discloses that 3-hydroxy-1-methacryloyloxyadamatane,  $\beta$ -methacryloyloxy- $\gamma$ -butyrolactone and  $\alpha$ -methacryloyloxy- $\gamma$ -butyrolactone are examples of acid labile (meth)acrylates (c. 6, l. 56-63). The third monomer of resin H meets the limitation of a nitrile moiety as set forth in instant claim 40. The first monomer of each of the resins A and H meet the limitation of an alicyclic acid labile ester group as set forth in instant claims 39. Furthermore the examiner is

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of the position that a silicon wafer meets the limitation of a microelectronic wafer substrate as set forth in instant claim 46.

Although, Fujishima fails to exemplify a polymer comprising a polymer that is a tetrapolymer it clearly teaches that taught resin (1) having recurring units of formula (I), (II) and (III) may also have polymerization units of formula (IV) α-methacryloyloxy-γ-butyrolactone or formula (V) maleic anhydride (p. 0008-0011 and 0014-0024). One of ordinary skill in the art would readily envisage a tetrapolymer comprising recurring unit of formula (I), (II), (III) such as that exemplified in resin H and a recurring unit of formula (IV) or formula (V) as disclosed in paragraphs 0008-0011.

Fujishima, as discussed above, teaches all the limitations of the instant claims except the presence of a polymerized norbornene group, however does suggest in p. 0022 that a norbornene-type unit may be included.

. Willson (US '445) teaches that the cycloaliphatic backbone of polymers having the

generic formula: (Fig. 1) serves to provide dry etch-resistance and thermal stability and also serves to tether the pendant functionalities required for imaging. The said system also has high sensitivity. The said polymer introduces a pendant acid cleavable group, which enhances adhesion and solubility of the material in aqueous base developing solvent (c. 15, l. 1-28). It is the examiner's position that the said generic formula meets the limitation of a polymerized norbornene group as set forth in the instant claims. One of ordinary skill in the art would have been motivated by the teachings of Willson to incorporate cycloaliphatic backbones

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having the said generic formula into the exemplified resins A or H of Fujishima in order to improve dry etch-resistance, thermal stability as well as sensitivity, adhesion and solubility of the formed material.

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## Response to Arguments

3. Applicant's arguments filed 11/5/2007 and 6/23/2008 have been fully considered but they are not persuasive. Applicant again argues that there is no motivation in the Fujishima (EP 982628 A2) reference to employ 4 recurring units to have a tetrapolymer or to include a norbornene groups. As discussed above, although, Fujishima fails to exemplify a polymer comprising a polymer that is a tetrapolymer it clearly teaches that taught resin (1) having recurring units of formula (I), (II) and (III) may also have polymerization units of formula (IV) α-methacryloyloxy-γ-butyrolactone or formula (V) maleic anhydride (p. 0008-0011 and 0014-0024). One of ordinary skill in the art would readily envisage a tetrapolymer comprising recurring unit of formula (I), (II), (III) such as that exemplified in resin H and a recurring unit of formula (IV) or formula (V) as disclosed in paragraphs 0008-0011. Also, Fujishima, teaches all the limitations of the instant claims except the presence of a polymerized norbornene group, however does suggest in [0022] that a norbornene-type unit may be included.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Amanda C. Walke whose telephone number is 571-272-1337. The examiner can normally be reached on M-R 5:30-4.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Cynthia Kelly can be reached on 571-272-1526. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Amanda C Walke Primary Examiner Art Unit 1795

/Amanda C Walke/ Primary Examiner, Art Unit 1795